



Attorney Docket No. 108298722US
Disclosure No. 02-1565.00/US

PTO/SB/08a/b (08-03)

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U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

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Substitute for form 1449A/B/PTO				Complete If Known	
				Application Number	10/665,908-Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	1	of	13	Attorney Docket Number	108298722US

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number		Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
KMS		US-10/767,298	Filed 01-28-2004	Zheng et al.	
KMS		US-11/027,825	Filed 12-29-2004	Derderian et al.	
KMS		US-10/933,604	Filed 09-02-2004	Carpenter et al.	
KMS		US-10/687,458	Filed 10-15-2003	Kubista et al.	
KMS		US-10/683,424	Filed 10-10-2003	Mardian	
KMS		US-10/839,316	Filed 05-05-2004	Saragiannis et al.	
KMS		US-10/814,573	Filed 03-31-2004	Gealy et al.	
KMS		US-11/043,629	Filed 01-25-2005	Rueger et al.	
KMS		US-11/018,142	Filed 12-20-2004	Rueger et al.	
KMS		US-10/840,571	Filed 05-06-2004	Dando et al.	
KMS		US-10/859,883	Filed 06-02-2004	Miller et al.	
KMS		US-10/683,606	Filed 10-09-2003	Derderian	
KMS		US-11/027,809	Filed 12-29-2004	Carpenter et al.	
KMS		US-579,269	03-23-1897	Hent	
KMS		US-3,618,919	11-09-1971	Beck	
KMS		US-3,620,934	11-16-1971	Endle	
KMS		US-3,630,881	12-28-1971	Lester et al.	
KMS		US-3,630,769	12-28-1971	Hart et al.	
KMS		US-3,634,212	01-11-1972	Valayli et al.	
KMS		US-4,018,949	04-19-1977	Donokowski et al.	
KMS		US-4,242,182	12-30-1980	Popescu	

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KMS	US-4,269,625	05-26-1981	Molenaar	
KMS	US-4,289,061	09-15-1981	Emmett	
KMS	US-4,397,753	08-09-1983	Czaja	
KMS	US-4,438,724	03-27-1984	Doebler et al.	
KMS	US-4,469,801	09-04-1984	Hirai et al.	
KMS	US-4,545,136	10-08-1985	Izu et al.	
KMS	US-4,590,042	05-20-1986	Drage	
KMS	US-4,681,777	07-21-1987	Engelken et al.	
KMS	US-4,826,579	05-02-1989	Westfall	
KMS	US-4,948,979	08-14-1990	Munakata et al.	
KMS	US-4,949,669	08-21-1990	Ishii et al.	
KMS	US-4,966,646	10-30-1990	Zdeblick	
KMS	US-4,977,106	12-11-1990	Smith	
KMS	US-5,076,205	12-31-1991	Vowles et al.	
KMS	US-5,091,207	02-25-1992	Tanaka	
KMS	US-5,131,752	07-21-1992	Yu et al.	
KMS	US-5,136,975	08-11-1992	Bartholomew et al.	
KMS	US-5,172,849	12-22-1992	Barten et al.	
KMS	US-5,200,023	04-06-1993	Gifford et al.	
KMS	US-5,223,113	06-29-1993	Kaneko et al.	
KMS	US-5,232,749	08-03-1993	Gilton	
KMS	US-5,248,527	09-28-1993	Uchida et al.	
KMS	US-5,364,219	11-15-1994	Takahashi et al.	
KMS	US-5,377,429	01-03-1995	Sandhu et al.	
KMS	US-5,380,396	01-10-1995	Shikida et al.	
KMS	US-5,409,129	04-25-1995	Tsukada et al.	
KMS	US-5,418,180	05-23-1995	Brown	
KMS	US-5,427,666	06-27-1995	Mueller et al.	
KMS	US-5,433,835	07-18-1995	Demaray et al.	
KMS	US-5,445,491	08-29-1995	Nakagawa et al.	
KMS	US-5,480,818	01-02-1996	Matsumoto et al.	
KMS	US-5,498,292	03-12-1996	Ozaki	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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KMS	US-5,500,256	03-19-1996	Watabe	
KMS	US-5,522,934	06-04-1996	Suzuki et al.	
KMS	US-5,536,317	07-16-1996	Crain et al.	
KMS	US-5,562,800	10-08-1996	Kawamura	
KMS	US-5,589,002	12-31-1996	Su	
KMS	US-5,592,581	01-07-1997	Okase	
KMS	US-5,595,606	01-21-1997	Fujikawa et al.	
KMS	US-5,599,513	02-04-1997	Masaki et al.	
KMS	US-5,624,498	04-29-1997	Lee et al.	
KMS	US-5,626,936	05-06-1997	Alderman	
KMS	US-5,640,751	06-24-1997	Faria	
KMS	US-5,643,394	07-01-1997	Maydan et al.	
KMS	US-5,654,589	08-05-1997	Huang et al.	
KMS	US-5,693,288	12-02-1997	Nakamura	
KMS	US-5,729,896	03-24-1998	Dalal et al.	
KMS	US-5,746,434	05-05-1998	Boyd et al.	
KMS	US-5,766,364	06-16-1998	Ishida et al.	
KMS	US-5,769,952	06-23-1998	Komino	
KMS	US-5,788,778	08-04-1998	Shang et al.	
KMS	US-5,792,700	08-11-1998	Turner et al.	
KMS	US-5,792,269	08-11-1998	Deacon et al.	
KMS	US-5,820,641	10-13-1998	Gu et al.	
KMS	US-5,827,370	10-27-1998	Gu	
KMS	US-5,833,888	11-10-1998	Arya et al.	
KMS	US-5,846,330	12-08-1998	Quirk et al.	
KMS	US-5,846,275	12-08-1998	Lane et al.	
KMS	US-5,851,849	12-22-1998	Comizzoli et al.	
KMS	US-5,865,417	02-02-1999	Harris et al.	
KMS	US-5,879,459	03-09-1999	Gadgil et al.	
KMS	US-5,895,530	04-20-1999	Shrotriya et al.	
KMS	US-5,908,947	06-01-1999	Vaartstra	
KMS	US-5,932,286	08-03-1999	Beinglass et al.	

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				Examiner Name	Rudy Zervigon
Sheet	4	of	13	Attorney Docket Number	108298722US
KMS	US-5,953,634	09-14-1999	Kajita et al.		
KMS	US-5,956,613	09-21-1999	Zhao et al.		
KMS	US-5,968,587	10-19-1999	Frankel		
KMS	US-5,972,430	10-26-1999	DiMeo, Jr. et al.		
KMS	US-5,994,181	11-30-1999	Hsieh et al.		
KMS	US-5,997,588	12-07-1999	Goodwin et al.		
KMS	US-6,008,086	12-28-1999	Schuegraf et al.		
KMS	US-6,032,923	03-07-2000	Biegelsen et al.		
KMS	US-6,042,652	03-28-2000	Hyun et al.		
KMS	US-6,045,620	04-04-2000	Tepman et al.		
KMS	US-6,059,885	05-09-2000	Ohashi et al.		
KMS	US-6,062,256	05-16-2000	Miller et al.		
KMS	US-6,070,551	06-06-2000	Li et al.		
KMS	US-6,080,446	06-27-2000	Tobe et al.		
KMS	US-6,079,426	06-27-2000	Subrahmanyam et al.		
KMS	US-6,086,677	07-11-2000	Umotoy et al.		
KMS	US-6,089,543	07-18-2000	Freerks		
KMS	US-6,109,206	08-29-2000	Maydan et al.		
KMS	US-09/651,037	08-30-2000	Mardian		
KMS	US-6,123,107	09-26-2000	Selser et al.		
KMS	US-6,129,331	10-10-2000	Henning et al.		
KMS	US-6,139,700	10-31-2000	Kang et al.		
KMS	US-6,143,659	11-07-2000	Leem		
KMS	US-6,143,077	11-07-2000	Ikeda et al.		
KMS	US-6,143,078	11-07-2000	Ishikawa et al.		
KMS	US-6,144,060	11-07-2000	Park et al.		
KMS	US-6,149,123	11-21-2000	Harris et al.		
KMS	US-6,160,243	12-12-2000	Cozad		
KMS	US-6,161,500	12-19-2000	Kopacz et al.		
KMS	US-6,174,366	01-16-2001	Ihantola		
KMS	US-6,174,377	01-16-2001	Doering et al.		
KMS	US-6,174,809	01-16-2001	Kang et al.		

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Substitute for form 1449A/B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known			
Sheet	5	of	13
			Attorney Docket Number
			108298722US

KMS	US-6,173,673	01-16-2001	Golovato et al.
KMS	US-6,178,660	01-30-2001	Emmi et al.
KMS	US-6,182,603	02-02-2001	Shang et al.
KMS	US-6,192,827	02-27-2001	Welch et al.
KMS	US-6,194,628	02-27-2001	Pang et al.
KMS	US-6,193,802	02-27-2001	Pang et al.
KMS	US-6,197,119	03-06-2001	Dozoretz et al.
KMS	US-6,200,415	03-13-2001	Maraschin
KMS	US-6,203,613	03-20-2001	Gates et al.
KMS	US-6,206,972	03-27-2001	Dunham
KMS	US-6,211,078	04-03-2001	Matthews
KMS	US-6,211,033	04-03-2001	Sandhu et al.
KMS	US-6,210,754	04-03-2001	Lu et al.
KMS	US-6,214,714	04-10-2001	Wang et al.
KMS	US-6,237,394	05-29-2001	Harris et al.
KMS	US-6,237,529	05-29-2001	Spahn
KMS	US-6,245,192	06-12-2001	Dhindsa et al.
KMS	US-6,255,222	07-03-2001	Xia et al.
KMS	US-6,263,829	07-24-2001	Schneider et al.
KMS	US-2001/0010309-A1	08-02-2001	Van Bilsen
KMS	US-6,270,572	08-07-2001	Kim et al.
KMS	US-2001/0011526-A1	08-09-2001	Doering et al.
KMS	US-6,280,584	08-28-2001	Kumar et al.
KMS	US-6,287,980	09-11-2001	Hanazaki et al.
KMS	US-6,287,965	09-11-2001	Kang et al.
KMS	US-6,291,337	09-18-2001	Sidhwa
KMS	US-6,290,491	09-18-2001	Shahvandi et al.
KMS	US-2001/0024387-A1	09-27-2001	Raaijmakers et al.
KMS	US-6,297,539	10-02-2001	Ma et al.
KMS	US-6,302,964	10-16-2001	Umotoy et al.
KMS	US-6,302,965	10-16-2001	Umotoy et al.
KMS	US-6,303,953	10-16-2001	Doan et al.

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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Sheet	6	of	13	Attorney Docket Number	108298722US
KMS	US-2001/0029892-A1	10-18-2001	Cook et al.		
KMS	US-6,305,314	10-23-2001	Sneh et al.		
KMS	US-6,309,161	10-30-2001	Hofmeister		
KMS	US-6,315,859	11-13-2001	Donohoe		
KMS	US-2001/0045187-A1	11-29-2001	Uhlenbrock		
KMS	US-6,329,297	12-11-2001	Ballsh et al.		
KMS	US-2001/0054484-A1	12-27-2001	Komino		
KMS	US-2002/0007790-A1	01-24-2002	Park		
KMS	US-6,342,277	01-29-2002	Sherman		
KMS	US-6,346,477	02-12-2002	Kaloyerous et al.		
KMS	US-6,347,602	02-19-2002	Goto et al.		
KMS	US-6,347,918	02-19-2002	Blahnik		
KMS	US-2002/0020353-A1	02-21-2002	Redemann et al.		
KMS	US-6,355,561	03-12-2002	Sandhu et al.		
KMS	US-6,358,323	03-19-2002	Schmitt et al.		
KMS	US-2002/0043216-A1	04-18-2002	Hwang et al.		
KMS	US-6,374,831	04-23-2002	Chandran et al.		
KMS	US-2002/0052097-A1	05-02-2002	Park		
KMS	US-6,387,185	05-14-2002	Doering et al.		
KMS	US-6,387,207	05-14-2002	Janakiraman et al.		
KMS	US-2002/0076508-A1	06-20-2002	Chiang et al.		
KMS	US-2002/0076490-A1	06-20-2002	Chiang et al.		
KMS	US-2002/0073924-A1	06-20-2002	Chiang et al.		
KMS	US-2002/0076507-A1	06-20-2002	Chiang et al.		
KMS	US-6,420,230	07-16-2002	Derderian et al.		
KMS	US-6,419,462	07-16-2002	Horie et al.		
KMS	US-6,420,742	07-16-2002	Ahn et al.		
KMS	US-2002/0094689-A1	07-18-2002	Park		
KMS	US-2002/0100418-A1	08-01-2002	Sandhu et al.		
KMS	US-6,428,859	08-06-2002	Chiang et al.		
KMS	US-2002/0104481-A1	08-08-2002	Chiang et al.		
KMS	US-6,432,831	08-13-2002	Dhindsa et al.		

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KMS	US-6,432,259	08-13-2002	Noorbaksh et al.		
KMS	US-6,432,256	08-13-2002	Raoux		
KMS	US-2002/0110991-A1	08-15-2002	Li		
KMS	US-2002/0108714-A1	08-15-2002	Doering et al.		
KMS	US-6,435,865	08-20-2002	Tseng et al.		
KMS	US-6,444,039	09-03-2002	Nguyen		
KMS	US-2002/0127745-A1	09-12-2002	Lu et al.		
KMS	US-6,450,117	09-17-2002	Murugesh et al.		
KMS	US-6,451,119	09-17-2002	Sneh et al.		
KMS	US-2002/0129768-A1	09-19-2002	Carpemter et al.		
KMS	US-6,458,416	10-01-2002	Derderian et al.		
KMS	US-6,461,931	10-08-2002	Eldridge		
KMS	US-6,461,436	10-08-2002	Campbell et al.		
KMS	US-2002/0144655-A1	10-10-2002	Chiang et al.		
KMS	US-2002/0146512-A1	10-10-2002	Roszman		
KMS	US-2002/0164420-A1	11-07-2002	Derderian et al.		
KMS	US-2002/0162506-A1	11-07-2002	Sneh et al.		
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KMS	US-2002/0197402-A1	12-26-2002	Chiang et al.		
KMS	US-2002/0195056-A1	12-26-2002	Sandhu et al.		
KMS	US-2003/0003730-A1	01-02-2003	Li		
KMS	US-2003/0000473-A1	01-02-2003	Chae et al.		
KMS	US-2003/0003697-A1	01-02-2003	Agarwal et al.		
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KMS	US-6,506,254	01-14-2003	Bosch et al.		
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KMS	US-2003/0023338-A1	01-30-2003	Chin et al.		
KMS	US-2003/0024477-A1	02-06-2003	Okuda et al.		
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KMS	US-10/365,085	02-11-2003	Carpenter et al.		
KMS	US-2003/0037729-A1	02-27-2003	DeDontney et al.		
KMS	US-6,534,395	03-18-2003	Werkhoven et al.		
KMS	US-6,534,007	03-18-2003	Blonigan et al.		
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KMS	US-6,540,838	04-01-2003	Sneh et al.		
KMS	US-6,541,353	04-01-2003	Sandhu et al.		
KMS	US-2003/0066483-A1	04-10-2003	Lee et al.		
KMS	US-2003/0070618-A1	04-17-2003	Campbell et al.		
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KMS	US-2003/0098372-A1	05-29-2003	Kim		
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KMS	US-6,579,374	06-17-2003	Bondestam et al.		
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KMS	US-6,602,346	08-05-2003	Gochberg		
KMS	US-2003/0159780-A1	08-28-2003	Carpenter et al.		
KMS	US-6,630,201	10-07-2003	Chiang et al.		
KMS	US-2003/0194862-A1	10-16-2003	Mardian et al.		
KMS	US-2003/0192645-A1	10-16-2003	Liu		
KMS	US-6,635,965	10-21-2003	Lee et al.		
KMS	US-6,638,879	10-28-2003	Hsieh et al.		
KMS	US-6,638,672	10-28-2003	Deguchi		

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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Disclosure No. 02-1565.00/US

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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				Complete If Known	
				Application Number	10/665,908-Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
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KMS	US-2003/0203109-A1	10-30-2003	Dando et al.	
KMS	US-2003/0200926-A1	10-30-2003	Dando et al.	
KMS	US-6,641,673	11-04-2003	Yang	
KMS	10/733,523	12-10-2003	Beaman et al.	
KMS	US-6,673,196	01-06-2004	Oyabu	
KMS	US-2004/0003777-A1	01-08-2004	Carpenter et al.	
KMS	US-2004/0007188-A1	01-15-2004	Burkhart et al.	
KMS	US-2004/0035358-A1	02-26-2004	Basceri et al.	
KMS	US-2004/0040502-A1	03-04-2004	Basceri et al.	
KMS	US-2004/0040503-A1	03-04-2004	Basceri et al.	
KMS	US-6,704,913	03-09-2004	Rossman	
KMS	US-6,706,334	03-16-2004	Kobayashi et al.	
KMS	US-6,705,345	03-16-2004	Bifano	
KMS	US-2004/0083959-A1	05-06-2004	Carpenter et al.	
KMS	US-2004/0083961-A1	05-06-2004	Basceri	
KMS	US-2004/0083960-A1	05-06-2004	Dando	
KMS	US-2004/0099377-A1	05-27-2004	Newton et al.	
KMS	US-2004/0124131-A1	07-01-2004	Aitchison et al.	
KMS	US-2004/0154538-A1	08-12-2004	Carpenter et al.	
KMS	US-6,818,249-B2	11-16-2004	Derderian	
KMS	US-2004/0226507-A1	11-18-2004	Carpenter et al.	
KMS	US-6,821,347-B2	11-23-2004	Carpenter et al.	
KMS	US-6,838,114-B2	01-04-2005	Carpenter et al.	
KMS	US-2005/0016984-A1	01-27-2005	Dando	
KMS	US-2005/0022739-A1	02-03-2005	Carpenter et al.	
KMS	US-2005/0028734-A1	02-10-2005	Carpenter et al.	
KMS	US-2005/0039680-A1	02-24-2005	Beaman et al.	
KMS	US-2005/0039686-A1	02-24-2005	Zheng et al.	
KMS	US-6,861,094-B2	03-01-2005	Derderian et al.	
KMS	US-2005/0045100-A1	03-03-2005	Derderian	
KMS	US-2005/0045102-A1	03-03-2005	Zheng et al.	
KMS	US-2005/0059261-A1	03-17-2005	Basceri et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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Attorney Docket No. 108298722US
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				Examiner Name	Rudy Zervigon
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FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Foreign Patent Document Country Code ³ -Number ⁴ -Kind Code ⁵ (If known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear -#
KMS		JP-4-213818-A	08-04-1992	Sony Corp	
KMS		JP-2001-82682-A	03-30-2001	Matsushita Refrig Co Ltd.	✓
KMS		JP-1-273991-A	11-01-1989	Ishikawajima Harima Heavy Ind. Co. Ltd.	
KMS		JP-63-256460-A	10-24-1988	Oki Electric Ind. Co. Ltd.	
KMS		WO-00/79019-A1	12-28-2000	Gadgil	
KMS		WO-03/016587-A1	02-27-2003	ASM Microchemistry OY, et al.	
KMS		WO-00/65649-A1	11-02-2000	Tokyo Electron Limited	
KMS		WO-03/008662-A2	01-30-2003	Applied Materials, Inc.	
KMS		WO-03/028069-A2	04-03-2003	Applied Materials, Inc.	
KMS		WO-02/095807-A2	11-28-2002	Integrated Materials, Inc.	
KMS		WO-02/073660-A2	09-19-2002	ASML US, Inc.	
KMS		WO-00/63952-A1	10-26-2000	Integrated Materials, Inc.	
KMS		WO-03/033762-A1	04-24-2003	Micron Technology, Inc.	
KMS		WO-02/45871-A1	06-13-2002	Angstrom Systems Inc.	
KMS		DE-198 51 824-A1	05-11-2000	Siemens AG	
KMS		WO-03/052807-A1	06-26-2003	Tokyo Electron Limited	
KMS		JP-9-82650-A	03-28-1997	Kokusai Electric Co. Ltd.	
KMS		JP-10-223719-A	08-21-1998	Dainippon Screen Mfg. Co. Ltd.	
KMS		JP-4-100533-A	04-02-1992	Mitsubishi Electric Corp.	
KMS		SU-598630	03-25-1978	Veremeichuk	
KMS		JP-2002-164336-A	06-07-2002	Sony Corporation	✓
KMS		WO-02/073329-A2	09-19-2002	Applied Materials, Inc.	
KMS		WO-03/035927-A2	05-01-2003	Applied Materials, Inc.	
KMS		WO-01/46490-A1	06-28-2001	Lam Research Corporation	
KMS		WO-98/37258-A1	08-27-1998	Moore Epitaxial Inc.	
KMS		WO-02/081771-A2	10-17-2002	Angstrom Systems, Inc.	
KMS		WO-99/06610-A1	02-11-1999	Applied Komatsu Technology, Inc.	
Examiner Signature	/Kelly Stouffer/			Date Considered	08/21/2006

Attorney Docket No. 108298722US
Disclosure No. 02-1565.00/US

PTO/SB/08a/b (08-03)

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		Art Unit	1763
		Examiner Name	Rudy Zervigon
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KMS	WO-02/48427-A1	06-20-2002	Tokyo Electron Limited	
KMS	EP-1 167 569-A1	01-02-2002	IPS Limited	
KMS	WO-00/40772-A1	07-13-2000	Genus, Inc.	
KMS	JP-11-172438-A	06-29-1999	Samsung Electron Co. Ltd.	✓
KMS	JP-8-34678-A	02-06-1996	Matsushita Electric Works Ltd.	✓
KMS	JP-6-151558-A	05-31-1994	Tokyo Electron Ltd.	✓
KMS	JP-6-342785-A	12-13-1994	Fujitsu Ltd.	✓
KMS	JP-2001-261375-A	09-26-2001	Toshiba Ceramics Co. Ltd.	✓
KMS	JP-2001-254181-A	09-18-2002	Tokyo Electron Ltd.	✓

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NON PATENT LITERATURE DOCUMENTS				
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		T ²
KMS		Integrated Process Systems Ltd., "ALD & CVD", 2 pages, retrieved from the Internet on December 11, 2001, < http://www.ips-tech.com/eng/pro-p2-2.htm >.		
KMS		Deublin Company, "Rotating Unions", 1 page, retrieved from the Internet on February 4, 2002, < http://www.com/products/rotatingunions.htm >.		
KMS		CAMERON, I., "Atomic Layer Deposition Chamber Works at Low Temperatures", 2 pages, Electronic Times, July 19, 2001, < http://www.electronicstimes.com/story/OEG20010719S0042 >.		
KMS		Cutting Edge Optronics, 600W QCW Laser Diode Array, Part Number: ARR48P600, 2 pages, October 2001, < www.ceolaser.com >.		
KMS		HENNING, A.K., et al., "Microfluidic MEMS for Semiconductor Processing," IEEE Trans. Components, Packaging, and Manufacturing Technology B21, pp. 329-337, 1998.		
KMS		FITCH, J.S., et al., "Pressure-Based Mass-Flow Control Using Thermopneumatically-Actuated Microvalves," Proceedings, Sensors and Actuators Workshop, pp. 162-165 (Transducers Research Foundation, Cleveland, OH, 1998).		
KMS		HENNING, A.K., "Liquid and gas-liquid phase behavior in thermopneumatically actuated microvalves," Proceedings, Micro Fluidic Devices and Systems (SPIE, Bellingham, WA, 1998; A.B. Frazier and C.H. Ahn, eds.), Vol. 3515, pp. 53-63.		

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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Substitute for form 1449A/B/PTO		Complete If Known			
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		Art Unit	1763		
		Examiner Name	Rudy Zervigon		
Sheet	12	of	13	Attorney Docket Number	108298722US
KMS	HENNING, A.K., et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing", 8 pages, Proceedings, SEMICON West Workshop on Gas Distribution (SEMI, Mountain View, CA, 1998).				
KMS	MAILLEFER, D., et al., "A High-Performance Silicon Micropump for Disposable Drug Delivery Systems," pp. 413-417, IEEE, 2001.				
KMS	HENNING, A.K., et al., "A thermopneumatically actuated microvalve for liquid expansion and proportional control", Proceedings, TRANSDUCERS '97: 1997 International Solid State Sensors and Actuators Conference, pp. 825-828.				
KMS	University of California, Berkeley, University Extension, "Atomic Layer Deposition," 5 pages, September 24-25, 2001, < http://www.unex.berkeley.edu/eng/br225/1-1.html >.				
KMS	ENGELKE, F., et al., "Determination of Phenylthiohydantoin-Amino Acids by Two-Step Laser Sesorption/Multiphoton Ionization," Analytical Chemistry, Vol. 59, No. 6, pp. 909-912, March 15, 1987, The American Chemical Society.				
KMS	COWIN, J.P., et al., "Measurement of Fast Desorption Kinetics of D2 From Tungsten By Laser Induced Thermal Desorption," Surface Science, Vol. 78, pp. 545-564, 1978, North-Holland Publishing Company.				
KMS	READY, J.F., "Effects Due to Absorption of Laser Radiation," Journal of Applied Physics, Vol. 36, No. 2, pp. 462-468, February 1965, Journal of Applied Physics, American Institute of Physics.				
KMS	ZARE, R.N., et al. "Mass Spectrometry of Molecular Adsorbates Using Laser Desorption/Laser Multiphoton Ionization," Bulletin of the Chemical Society of Japan, Vol. 61, No. 1, pp. 87-92, January 1988.				
KMS	Tokyo Electron Limited, Plasma Process System, Trias SPA, 1 page, retrieved from the Internet on October 16, 2004, < http://www.tel.com/eng/products/spe/sdriasspa.htm >.				
KMS	OLSSON, A., "Valve-less Diffuser Micropumps", ISSN 0281-2878, 66 pages, 1998.				
KMS	BARDELL, R.L., et al., "Designing High-Performance Micro-Pumps Based on No-Moving-Parts Valves", DSC-Vol. 62/HTD-Vol. 354, Microelectromechanical Systems (MEMS) ASME 1997, pp. 47-53.				
KMS	HENNING, A.K., et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings, Micromachined Devices and Components (SPIE, Bellingham, WA, 1998; P.J. French and K. Chau, eds.), Vol. 3514, pp. 159-170.				
KMS	HENNING, A.K. et al., "Contamination Reduction Using MEMS-BASED, High-Precision Mass Flow Controllers," Proceedings, SEMICON West Symposium on Contamination Free Manufacturing for Semiconductor Processing (SEMI, Mountain View, CA, 1998), pp. 1-11.				
KMS	HENNING, A.K., "Microfluidic MEMS," Proceedings, IEEE Aerospace Conference, Paper 4.906 (IEEE Press, Piscataway, NJ, 1998), 16 pages.				

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
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Attorney Docket No. 108298722US
Disclosure No. 02-1565.00/US

PTO/SB/08a/b (08-03)

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				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	13	of	13	Attorney Docket Number	108298722US
KMS	PETERS, L., "Thermal Processing's Tool of Choice: Single-Wafer RTP or Fast Ramp Batch?" Semiconductor International, April 1, 1998, 8 pages, < http://www.e-incite.net/semiconductor/index.asp?alyout+article&articleId=CA163937 >.				
KMS	The University of Adelaide, Australia, Department of Chemistry, "Spectroscopy", 2 pages, retrieved from the Internet on February 9, 2002, < http://www.chemistry.adelaide.edu.au/external/Soc-Rel/Content/spectros.htm >.				
KMS	Deublin Company, "Sealing," 2 pages, retrieved from the Internet on February 4, 2002, < http://www.deublin.com/products/sealing.htm >.				
KMS	Deublin Company, "Precision Rotating Connections for Water, Steam, Air, Hydraulic, Vacuum, Coolant and Hot Oil Service," 1 page, retrieved from the Internet on February 4, 2002, < http://www.deublin.com >.				
KMS	Integrated Process Systems Ltd., "Nano-ALD", 2 pages, retrieved from the Internet on December 11, 2001, < http://www.ips-tech.com/eng/pro-p2.htm >.				
KMS	Integrated Process Systems Ltd., "Welcome to IPS Ltd.", 1 page, retrieved from the Internet on December 11, 2001, < http://www.ips-tech.com/eng/main.htm >.				
KMS	TAKAHASHI, K et al., "Process Integration of 3D Chip Stack with Vertical Interconnection," pp. 601-609, 2004 Electronic Components and Technology Conference, IEEE, June 2004.				

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